## **RESEARCH PAPER**

# Millimeter-wave hetero-integrated sources in InP-on-BiCMOS technology

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The paper presents millimeter-wave (mm-wave) signal sources using a hetero-integrated InP-on-BiCMOS semiconductor technology. Mm-wave signal sources feature fundamental frequency voltage-controlled oscillators (VCOs) in BiCMOS, which drive frequency multiplier-amplifier chains in transferred-substrate (TS) InP-DHBT technology, heterogeneously integrated on top of the BiCMOS wafer in a wafer-level bonding process. Both circuits are biased through a single set of bias pads and compact low-loss transitions from BiCMOS to InP circuits and vice versa have been developed, which allows seamless signal routing through both technologies exhibiting 0.5 dB insertion loss up to 200 GHz. One VCO operates at 82 GHz with a tuning range of 600 MHz and an output power of approximately 8 dBm. A frequency doubler combined with this VCO circuit delivers o dBm at 164 GHz and a frequency tripler with a similar VCO delivers – 10 dBm at 246 GHz. Another hetero-integrated W-band doubler-amplifier circuit demonstrates 12.9 dBm saturated output power with 5.9 dB conversion gain at 96 GHz. A direct comparison of the TS InP-DHBT MMIC with either silicon or traditional AlN carrier substrates shows the favorable properties of the hetero-integrated process discussed here. The results demonstrate the feasibility of hetero-integrated circuits operating well above 100 GHz.

Keywords: New and emerging technologies and materials, technologies and devices (III-V, nano, quantum, opto)

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## I. INTRODUCTION

Millimeter-wave (mm-wave) applications demand for complex integrated circuit, well beyond the capabilities of today's microwave MMIC technologies. CMOS/BiCMOSbased mm-wave MMICs have achieved impressive results well beyond 100 GHz, but with low-power capabilities and aggressive scaling. Compound semiconductor technologies, such as InP technologies, exhibit higher breakdown voltages and higher frequency performance capabilities with relatively relaxed scaling. Thus, InP technology offers better power capabilities and higher breakdown voltage at similar maximum frequency of oscillation (fmax) values and enables access to even higher frequencies as compared to BiCMOS with similar technological dimensions. In order to achieve high output power levels at mm-wave frequencies and beyond with low-noise properties and complex integrated circuit, it would be desirable to merge these two separate technologies.

With this background as a motivation, work on heterointegration of different semiconductor technologies with

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<sup>3</sup>J. W. Goethe Universität Frankfurt/M, Frankfurt/M, Germany Corresponding author: V. Krozer Email: viktor.krozer@fbh-berlin.de complementary functionality is picking up speed. Most notably, research in InP-on-BiCMOS within a DARPA-funded consortium has to be mentioned (see, e.g. [1, 2]), but also activities on combining GaN-on-Si CMOS are ongoing [3]. Driven by automotive applications and high-speed backhaul links, a lot of experience has been accumulated with BiCMOS circuits in the *E*-band [4, 5], whereas InP HEMT and DHBT technologies have been applied widely in high-speed communications, such as 100 G fiber communications [6] or mm-wave wireless communications [7, 8].

In this work, we demonstrate the unique capabilities, which can be achieved with hetero-integrated InP-on-BiCMOS mm-wave MMIC. Special emphasis is given to signal sources, due to the lack of powerful low-noise signal sources at frequencies beyond 100 GHz. An important aspect in the development of the wafer-level hetero-integrated process is the implementation of low-loss transitions from one technology to the other, capable of operation well beyond 100 GHz. All circuits discussed here employ dedicated transitions with low-loss performance up to 200 GHz, as discussed below. A number of various combined circuits have been realized, such as frequency multipliers in InP driven by BiCMOS voltage-controlled oscillator (VCO) sources. In particular, this paper describes in detail a 164 GHz signal source that employs an 82 GHz fundamental frequency VCO in BiCMOS to drive a frequency doubler and amplifier chain in a transferred-substrate (TS) InP-DHBT technology [9]. An additional circuit presented in this paper operates at 96 GHz with higher output power levels. Both technologies are integrated using a wafer-level hetero-integration benzocyclobutene (BCB) bonding process. This approach is a joint effort of the two Leibniz research institutes FBH and IHP and will pave the way toward additional applications such as high-resolution and highly directive radars, imaging, or highspeed communications in the lower THz range. It is shown that changing the carrier substrate for the TS-InP process from the usual AlN to a BiCMOS substrate does not greatly influence the power-handling properties of InP-DHBT MMIC circuits, which remain also unaffected by the BiCMOS structures underneath, for example, fillers, lines, etc.

The following sections of the paper describe the combined InP-on-BiCMOS circuit as well as the individual circuit components in the BiCMOS and TS-InP technologies. A demonstration of the performance of the crucial interconnections to 200 GHz is provided. The fact that replacing the AlN substrate with a BiCMOS substrate does not degrade InP-DHBT power performance is shown with a 96 GHz doubler circuit and finally it is demonstrated that InP-DHBT circuit performance is essentially unchanged regardless of the substrate being employed.

### II. OVERALL CONCEPT

All hetero-integrated MMICs are based on signal sources in BiCMOS followed by an InP MMIC with on-chip transitions between the two blocks. As an example, a block diagram of the hetero-integrated 164 GHz MMIC signal source is shown in Fig. 1. The hetero-integration technology has been described in [10, 11] in full detail. Here, we will describe only the most important steps. The process starts with a fully standard BiCMOS processing. After finalizing the BiCMOS processing up to the top metals, a planarization step is introduced, which provides a surface with a topography of <100 nm across the wafer. The BiCMOS wafers are then cut-out into several 3" wafers. Independently, the transfer-substrate InP process is performed with scaled dimensions, which are determined by the mismatch between the thermal expansion coefficients. This means that the InP circuits are pre-scaled such that at around 200°C both the BiCMOS and the InP MMIC have exactly the same dimensions. Subsequently, both wafers are assembled using a BCB-bonding step. All transitions are formed in that bond process on wafer-level with an alignment accuracy of  $<6 \,\mu m$  across the wafer. The semiconductor



Fig. 1. Block diagram of hetero-integrated 164 GHz MMIC signal source; right-hand pads indicate the single-ended RF output, DC pads can be seen above and below the circuit. Green area is SiGe BiCMOS only and yellow area denotes InP-on-BiCMOS.

hetero-integration technology employed consist of a SiGe-BiCMOS process (SG25H1) in a high-performance 0.25  $\mu$ m technology with npn-HBTs up to  $f_T/f_{max} = 180/220$  GHz and a TS-InP-DHBT technology with  $f_T/f_{max}$  values of 350/ 350 GHz (for a one-finger HBT with an emitter area of 0.8 × 5  $\mu$ m<sup>2</sup>). A detailed description of this process is beyond the scope of this paper, but can be found in [12, 11].

In Fig. 1, an 82 GHz VCO is realized in BiCMOS, followed by a frequency doubler-amplifier chain using the TS-InP-DHBT process on top of the already manufactured BiCMOS circuits.

Stacking InP circuits on top of the BiCMOS structure will inevitably result in a detuning of the BiCMOS circuits, in our case primarily the VCO's resonant frequency. This effect is small since signals in the BiCMOS structures remain within the CMOS dielectric stack and do not interact with metallization in InP because the ground (Gd) InP layer is connected to SiGe ground layer. The main detuning effect is the low permittivity BCB ( $\varepsilon_r = 2.65$ ) on top of the BiCMOS elements, which can be fully eliminated if one takes into consideration the BCB stack already during BiCMOS circuit design.

In order to ensure first pass design, it was decided to place the BiCMOS and InP circuit parts offset from each other, so that the risk of undesired interference is minimized. A full three-dimensional integration approach will be explored in forthcoming runs with a stack of MMICs in both technologies directly on top of each other, providing considerably more compact circuits. Undesired coupling between circuit elements will also be investigated, because of its potential to trigger instabilities within the MMIC.

In the micrograph in Fig. 2, the complete circuit is shown. The VCO tank circuit can be seen on the left, in the center the BiCMOS–InP via interconnect, and the TS-InP circuit on the right. Interconnects can be placed everywhere in the circuit and daisy chain with transitions from InP to SiGe and back to InP circuits have been already explored. The combined circuit size is  $1 \times 3 \text{ mm}^2$  and the InP part covers  $1 \times 1.77 \text{ mm}^2$ . The BiCMOS circuit becomes visible because in the InP part all elements and metallization patterns are blanked out and hence only the transparent BCB layer remains in this area.

### III. THE LOW-LOSS BICMOS TO INP TRANSITIONS

Low-loss transitions between the BiCMOS and InP circuit parts are of paramount importance for the hetero-integrated circuits. Transitions have to be optimized in terms of size and RF loss. The transitions employed here have a diameter of 10  $\mu$ m, but 5  $\mu$ m vias have also been successfully realized. Due to the miniaturized structures and thanks to optimization



Fig. 2. Micrograph of the 164 GHz hetero-integrated source; the VCO structure is visible on the left and RF output pads can be seen on the right.



Fig. 3. Test structures with transitions between the top InP microstrip layer and the top metal layer in the BiCMOS process. The vias next to the InP microstrip line ensure that a common ground is shared between the InP and BiCMOS circuit parts.

using electromagnetic simulations, a return loss better than 12 dB from DC to beyond 200 GHz and an insertion loss below 0.4 dB up to 100 GHz and below 1 dB up to 220 GHz is achieved [12–14]. The reliability of such a transition can be verified with a chain of transitions, where misalignment and connection errors will cascade if there is a problem with the bonding process and/or the electromagnetic optimization.

A test structure of cascaded transitions from microstrip lines on InP to those on BiCMOS and vice versa is shown in Fig. 3. It consists of a total of ten transitions alternating between top metal on the InP layer and top metal on the BiCMOS layer. Its insertion and return loss was measured up to 110 GHz.

It can be observed in Fig. 3 that the signal via is not perfectly in the centre of the via catch pad, but it is sufficiently accurate to achieve good high-frequency behavior. S-parameters measured on-wafer from 50 MHz to 110 GHz are plotted in Fig. 4 for the structure in Fig. 3. The figure shows the insertion loss and reflection coefficients for six samples across the wafer overlaid. Dividing by the number of transitions, assuming that the line losses are negligible, and noting that the return loss is better than 10 dB to beyond 110 GHz, we can estimate a loss of <0.35 dB/transition at 100 GHz and <0.5 dB/transition at 200 GHz.

The results are very encouraging and demonstrate that a reliable connection can be established between the BiCMOS and InP circuit layers with low loss and without placement restrictions within the circuit. The uniform response from multiple identical structures measured across the wafer demonstrates high reproducibility of the interconnection.

DC biasing of the BiCMOS VCO and buffer as well as the three TS-InP-DHBTs is all done through DC pads on the top InP metallization layer. A continuous ground plane is located between the InP circuit area and the BiCMOS wafer. This ensures a low-loss thin-film microstrip wiring environment in the InP part, without interaction with the SiGe BiCMOS circuitry and prevents higher losses associated with the silicon substrate below. An exception to this is the area beneath the series capacitors in the high-frequency signal path, where an opening in the ground plane is made to reduce the parasitic capacitance between the ground plane and the lower capacitor plate.

It was not well established prior to the run if the fillers in the SiGe process will affect the performance of the InP circuit in the areas, where the ground is open. This has been investigated on individual devices together with possibilities for integrated thermal heat sinks in SiGe.

### IV. DEVICE RF PERFORMANCE

The performance of InP-DHBT devices on top of the SiGe BiCMOS stack has been compared to that of the original TS-InP-DHBT process. Small-signal and large-signal operations have been investigated. Figure 5 illustrates a comparison of the TS-InP-DHBT and of the InP-on-BiCMOS InP-DHBT operation with the device model available at FBH. The device model accurately represents measured results for a single-finger transistor, whereas it is slightly optimistic for a double-finger device. Large-signal performance measured for different shots across the wafer are also provided in Fig. 5(b), which demonstrates rather good uniformity. The results indicate that highoutput powers can be obtained from both processes and the hetero-integration InP-on-BiCMOS process does not deteriorate significantly the performance of the active devices.

Small-signal measurements have also been performed to investigate the impact of fillers in SiGe and thermal heat sinks in SiGe for the top InP circuits on active device performance. Figure 6 shows small-signal measurement comparison between the original and the hetero-integrated S11 and S22. From Fig. 6, it can be concluded that there is only a minor impact by the fillers in SiGe on InP HBT performance. This is most probably due to the fact that the filler structures are small and non-interconnected. Also a structure underneath the InP-DHBT transistor structures, which is connects the Si substrate with the top metal in SiGe does not impact smallsignal performance and provides a heat-sink for the dissipated power in the transistor.



Fig. 4. Transmission (left) and reflection (right) properties of six identical multi-transition structures measured on the same wafer to 110 GHz.



Fig. 5. Large-signal performance of single-finger DHBT in TS process at 77 GHz (a) and double-finger DHBT in InP-on-BiCMOS process at 96 GHz (b). Dots represent simulations, solid lines are measurements.



Fig. 6. Small-signal performance of single-finger DHBT in TS process and the same device with fillers in the InP-on-BiCMOS process (a) and implementing a heat-sink underneath the transistor in SiGe (b). Measurements are in the range 1–110 GHz. Cyan and blue lines are results for the standard TS process, red and magenta are results for InP HBT transistors in InP-on-BiCMOS process. Insets show the transistor layout for the two cases, respectively.

## V. MMIC CIRCUIT DESIGN

## A) BiCMOS circuit

The oscillator features a differential Colpitts topology, which has been a common choice in mm-range VCOs for low-phase noise applications. Its simplified schematic in Fig. 7 shows a modified differential Colpitts topology with inductance LE2 in parallel, and inductance LE1 in series to the varactor. Adding LE1 and LE2 reduces oscillator phase noise by increasing the loaded quality factor of the resonant circuit compared to the case of a pure varactor.

From the Leeson formula, it is clear that we have to increase Q-factor of the tank and voltage swing in the tank to minimize the oscillator phase noise. In the mm-wave range *Q*-factor is primarily limited by the varactor. A differential MOS varactor with lower resistance was used. It exhibits two MOS varactors, which are connected directly in silicon. This silicon connection has small resistivity because the varactors are just 0.3  $\mu$ m apart. This structure avoids contacts from *N*-well to Metal1 reducing varactor resistance, and hence increasing the varactor *Q*. There is an additional contact to the *N*-well for hole extraction, which are generated at negative gate voltages.

Inductances, shown in the schematic, are realized in layout by transmission lines. The top metal layer, with a thickness of 3  $\mu$ m, is used for the signal line. It is 9  $\mu$ m above the bottom metal layer, which forms the ground plane.

The VCO is followed by a single-stage buffer that features cascode topology. The buffer is inserted to provide isolation



Fig. 7. Simplified schematic of the differential Colpitts VCO and output buffer.

between the VCO core and the rest of the circuit. For this purpose, the cascode topology provides good isolation and matching.

## **B) TS-InP-DHBT** circuit

The TS-InP-DHBT part of the circuit consists of a 164 GHz doubler and a two-stage amplifier. The schematic circuit is shown in Fig. 8. All three stages use the same two-finger HBT with an emitter size of  $0.8 \times 5 \ \mu\text{m}^2$ . Biasing for each TS-InP-DHBT stage can be independently controlled for optimum bias point adjustment. This is mostly a concern for the doubler stage, which operates under large-signal conditions. The expected power of the second harmonic is at a level where the subsequent amplifying stages have to be optimized for highest gain.

Simulated results of the cascaded doubler-amplifier chain are used in the following discussion to explain the design methodology and understanding the single-ended measured results. The characterization of the circuit can be performed only in conjunction with the BiCMOS VCO.

The doubler employs a single-ended topology with the input matched to the VCO target frequency of 85 GHz and the output to the second harmonic.

In order to suppress the fundamental frequency, a notch filter is implemented, which consists of an open-circuited



**Fig. 8.** Three stage InP doubler–amplifier chain; the first stage is the doubler. Each stage operates with a collector voltage of 1.5 V and a collector current of  $\sim$ 20 mA for the given results, but independent bias of each stage is possible.

stub with a radial stub at the end to reduce the length needed to suppress the fundamental frequency. The filter is narrow band, but provides good attenuation of the third harmonic as well. The total suppression of the fundamental frequency in the doubler–amplifier chain is 12 dB at the center frequency. An amplifier with two cascaded common-emitter HBTs is boosting the power of the second harmonic to the milliwatt level. According to simulations, the input return loss is expected to be better than 10 dB in the 77–115 GHz frequency range and the output return loss better than 10 dB in the 141–193 GHz range. The simulated S-parameters for the TS-INP-DHBT doubler–amplifier chain are plotted in Fig. 9.

The actual VCO frequency was 82 GHz instead of the expected 85 GHz. This does not significantly affect interstage matching in the circuit of Fig. 8, because simulated input and output return loss have good broadband properties, with  $\sim$ 13 and 14 dB, at 82 and 164 GHz, respectively. But, the effect of the notch filter is unfortunately greatly reduced, which can be seen from the  $S_{21}$  curve in Fig. 9. The suppression of the fundamental frequency is only o dB due to the frequency shift, which might adversely affect the amplifying stages. But it is not influencing the power meter reading due to the use of probe waveguides with cut-off frequencies above the fundamental frequency as explained in the measurement section. The graph in Fig. 10 presents simulated conversion gain and output power of the first and second harmonic based on the actual fundamental frequency of 82 GHz. The output power of the undesired first harmonic is guite constant at 2 dBm for the input power range from 0 to 10 dBm. For an expected VCO power of 6-8 dBm, the second harmonic output power is simulated to be around 2 dBm. Simulated conversion loss for the doubler alone is 11 dB, but the two-stage amplifier is expected to provide  $\sim 6$  dB gain at 164 GHz.

## C) Measurements on the 164 GHz MMIC signal source

The circuit is probed on-wafer with a G-band probe with a pitch of 75  $\mu$ m and connected to a WRo5 waveguide. A WRo5-WR10 waveguide taper provides a transition to the input of an Ericson PM4 power meter. The loss from probetip to power sensor is estimated to be 3 dB using an on-wafer standard. The cut-off frequency of the WRo5 waveguide is 112 GHz, which ensures that no power from the fundamental frequency is registered in the power measurement. The power level of the third harmonic is approximately



Fig. 9. Simulated S-parameters of the TS InP doubler-amplifier chain.



Fig. 10. Simulated conversion gain (CG) and output power of the first and second harmonic for the doubler-amplifier chain. Assumed fundamental frequency is 82 GHz. Actual input power was measured to be about 8 dBm.

20 dB lower than the second harmonic according to simulations and should thus have a negligible influence on the measurement. The measured output power is 0 dBm, which is not far from the expected value simulated in Fig. 10.

A second version of the circuit featuring a simple microstrip through-line replacing the doubler-amplifier chain was also available on the wafer and enabled direct measurement of the VCO spectrum and power. The results are plotted in Fig. 11, the spectrum was measured with an external *W*-band down-conversion mixer exhibiting a conversion loss of approximately 35-40 dB. De-embedding this, one obtains for the VCO only circuit an output power of 4.8 dBm, measured using an Agilent W8486A *W*-band power sensor connected with a WR10 waveguide to the RF probe. A tunable frequency range of 81.8–82.4 GHz for the VCO could be determined with less than 0.2 dB variation in the output power.

This is the first circuit of its kind in this frequency range, which makes benchmarking difficult. However, in [7] a source is described based on a pure InP-HBT *G*-band VCO plus a doubler/quadrupler, which achieves -2 dBm in the 113–118 GHz band and -4 dBm in the 212–228 GHz band. The present realization with 0 dBm at 164 GHz compares well with this data.



Fig. 11. 82 GHz VCO output spectrum measured on the InP-on-BiCMOS wafer.



**Fig. 12.** Single-ended 96 GHz doubler-amplifier in InP with silicon substrate. Notice that the mandatory fillers in the silicon part are removed around parts of the InP circuit where openings in the ground plane occur.

## D) Hetero-integrated InP-DHBT 96-GHz doubler and amplifier

As described above, the active InP-HBT device performance has not deteriorated when hetero-integrated with SiGe BiCMOS. This has also been tested on the MMIC level. A 96-GHz doubler with and without power MMIC amplifier was implemented in InP-DHBT process on top of the SiGe BiCMOS. This was done in order to verify whether the power capabilities of TS-InP circuits would be compromised using a silicon substrate having a lower thermal conductivity than, e.g. AlN.

The doubler is a single-ended design, see Fig. 12, with the same basic methodology as used for the 164-GHz doubler.

The measured on-wafer small-signal S-parameters of the doubler-amplifier can be seen in Fig. 13.

The suppression of the fundamental frequency with the notch filter is clearly visible from  $S_{21}$ . The output is well matched over most of *W*-band. The input, however, is matched less well, with a return loss of  $\sim 8$  dB.

The circuit uses the same two-finger HBT as in the 164-GHz doubler circuit. Optimum conversion gain is 8.3 dB with an output power of 9 dBm at 96 GHz. The saturated output power is 12.6 dBm with a conversion loss of 5.9 dB. The DC power consumption is 90 mW for the optimum conversion gain case and 115 mW under saturated operation for the combined two stages. The  $P_{IN}$ - $P_{OUT}$  and conversion gain curves versus input power, for a constant bias point, can be seen in Fig. 14. In the same figure, the  $P_{IN}$ - $P_{OUT}$  and conversion gain is also plotted (see dotted



Fig. 13. Measured S-parameters of the 96 GHz doubler-amplifier circuit.



**Fig. 14.**  $P_{IN}$ – $P_{OUT}$  and conversion gain for the 96 GHz doubler–amplifier (solid lines) and doubler only (dots). Best conversion gain is achieved with an input power of 0 dBm, yielding an output power of 9 dBm.



Fig. 15. S-parameters of 96 GHz doublers with similar circuit topology, one with BiCMOS substrate (solid line) and one with AlN substrate (dashed line).

curve) for the doubler part only, which has been measured independently. The figure demonstrates the improved gain,  $\sim$ 4 dB, when the doubler is operated in saturation, and the output power performance of the combined circuit versus the doubler alone.

Figure 15 shows the S-parameters of two 96 GHz doublers with practically identical circuit layout, again using a singleended doubler design based on two-finger HBTs. One doubler circuit is using the standard AlN substrate; the other is using the BiCMOS silicon substrate. The only difference in the layout is that the InP-on-BiCMOS circuit is biased through bias tees and the InP-on-AlN is biased using separate DC pads. The circuits were biased at rather high DC current densities,  $\sim$  3.7 mA/µm<sup>2</sup>, but there is no obvious degradation due to the use of the BiCMOS substrate with lower thermal conductivity.

### VI. CONCLUSION

This paper demonstrates successful implementation of mmwave MMICs using a new hetero-integration InP-on-BiCMOS technology. To the authors' knowledge, the paper also shows the first ever published BiCMOS/InP heterointegrated MMIC in W-band and above. We prove that waferlevel integration of TS-InP and BiCMOS circuits is possible without degrading circuit performance. We also clearly demonstrate the overall benefits in performance outreaching the limits of each individual technology.

The circuit design was performed without any modifications to the transistor models accounting for the stacked approach, so the agreement between measurements and simulations also documents that the hetero-integration does not diminish circuit behavior. Direct comparison of similar circuits using either AlN or silicon substrates show that there is no fundamental change in performance. Reproducible, low loss, and broadband interconnects up to 200 GHz are now available for the demonstrated InP-on-BiCMOS technology to accommodate signal routing between both material systems using complex transmission line circuitry, which is no longer a limiting factor.

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